

WHAT IS CLAIMED IS:

1. A thin film formation apparatus comprising:  
a head portion having an ultrasonic oscillator; and  
a nozzle filled with an application liquid for forming an EL layer.
2. A thin film formation apparatus comprising:  
a head portion having an ultrasonic oscillator; and  
a nozzle filled with an application liquid for forming an EL layer,  
wherein said nozzle has a heater.
3. A thin film formation apparatus according to claim 2, wherein said nozzle has a  
large internal diameter portion and a small internal diameter portion, and  
said heater is formed in said small internal diameter portion.
4. A thin film formation apparatus according to claim 2, wherein the small internal  
diameter portion of the nozzle has a contact element.
5. A thin film formation apparatus according to claims 1 or 2, wherein said  
application liquid in said nozzle is pressurized by ultrasonic oscillations, and is pushed out  
from said nozzle.
6. A method of manufacturing a self-light-emitting device, comprising the steps of:  
filling a nozzle with an application liquid for forming an EL layer; and  
applying said application liquid to a pixel column in accordance with applying

ultrasonic oscillations or heat.

7. A method of manufacturing a self-light-emitting device according to claim 6,

wherein:

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said nozzle has a large internal diameter portion and a small internal diameter portion;

said small internal diameter portion has a heater; and

said heater applies heat to the application liquid filling the nozzle.

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8. A method of manufacturing a self-light-emitting device, comprising the steps of :

imparting ultrasonic oscillations to a nozzle of a head portion by using an ultrasonic oscillator; and

imparting ultrasonic oscillations to an application liquid filling said nozzle by using said ultrasonic oscillator.

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9. A method of manufacturing a self-light-emitting device according to claim 8,  
wherein a heater of said nozzle applies heat to said application liquid filling said nozzle.

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10. A method of manufacturing a self-light-emitting device according to claims 6 or 8, wherein said application liquid is pushed out from said nozzle in accordance with pressurization, and is applied.

11. A method of manufacturing a self-light-emitting device according to claims 6 or 8, wherein said application liquid is pushed out from said nozzle in accordance with: capillary

action; the weight of said application liquid; or pressure; and is applied.

12. A method of manufacturing a self-light-emitting device according to claims 6 or 8, wherein said application liquid filling said nozzle is applied in accordance with a contact element of said nozzle contacting a bank.

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